



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: *Baer et al.* ) Group No.: 1763  
Serial No.: 10/675,697 )  
Filed: 09/30/2003 ) Examiner: Arancibia  
   ) Docket No.: HSJ9-2003-0032US1

For: **"METHOD OF FORMING A READ SENSOR USING PHOTORESIST  
STRUCTURES WITHOUT UNDERCUTS WHICH ARE REMOVED  
USING CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF  
PROCESSES"**

*OK*  
*to enter*  
*100-112005*  
*9/11/2005*

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*Entered with RCE*  
*9/26/05*  
*MW 9/29/05*

Sir:

**REQUEST FOR RECONSIDERATION**

The Applicant respectfully submits this Request for Reconsideration in response to the Office Action mailed on 23 May 2005 from Examiner Maureen Gramaglia Arancibia.